

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Smith, *et al.*

Docket No.: 2001 P 11900 US01

Serial No.: TBD

Art Unit: TBD

Filed: Herewith

Examiner: TBD

For: Method of Removing PECVD Residues of Fluorinated Plasma Using In-SITU H₂
Plasma

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

Prior to examination on the merits, Applicants respectfully submit this Preliminary
Amendment as set forth below: